FIG. 1

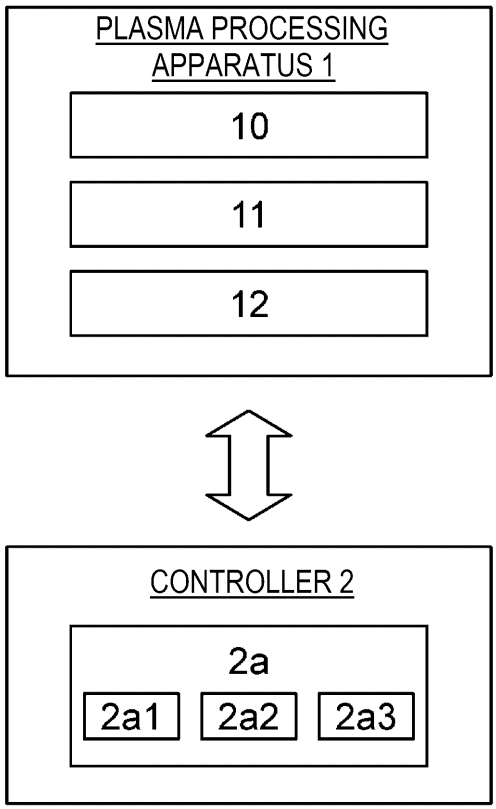

PLASMA PROCESSING APPARATUS 1
10
11
12
CONTROLLER 2
2a
2a1
2a2
2a3

FIG. 2

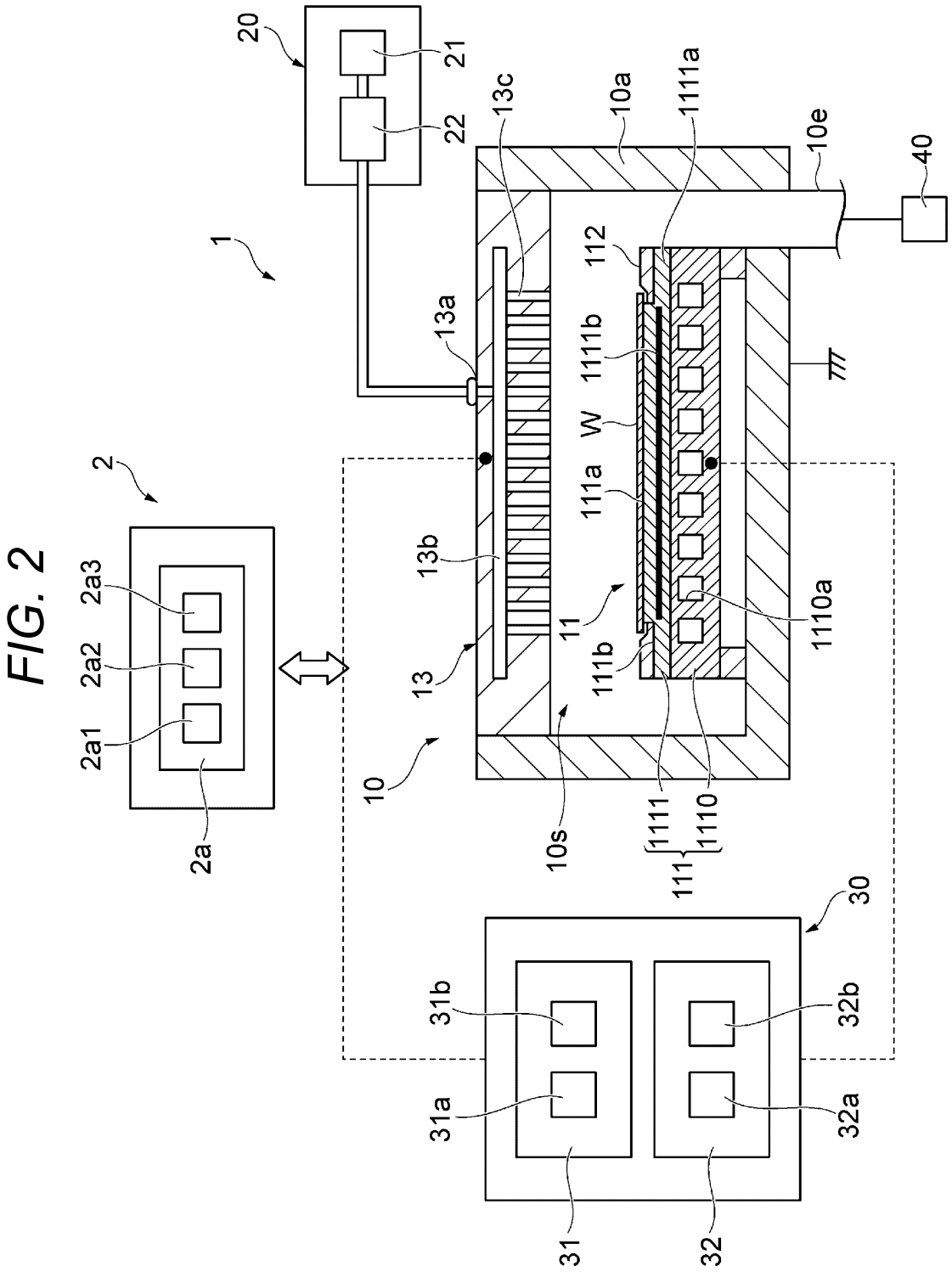

20
21
22
13c
10a
1111a
10e
40
1
112
13a
1111b
W
111a
2
2a3
2a2
2a1
13b
11
1110a
13
111b
10
10s
1111
1110
111
30
31b
32b
31a
32a
2a
31
32

FIG. 3

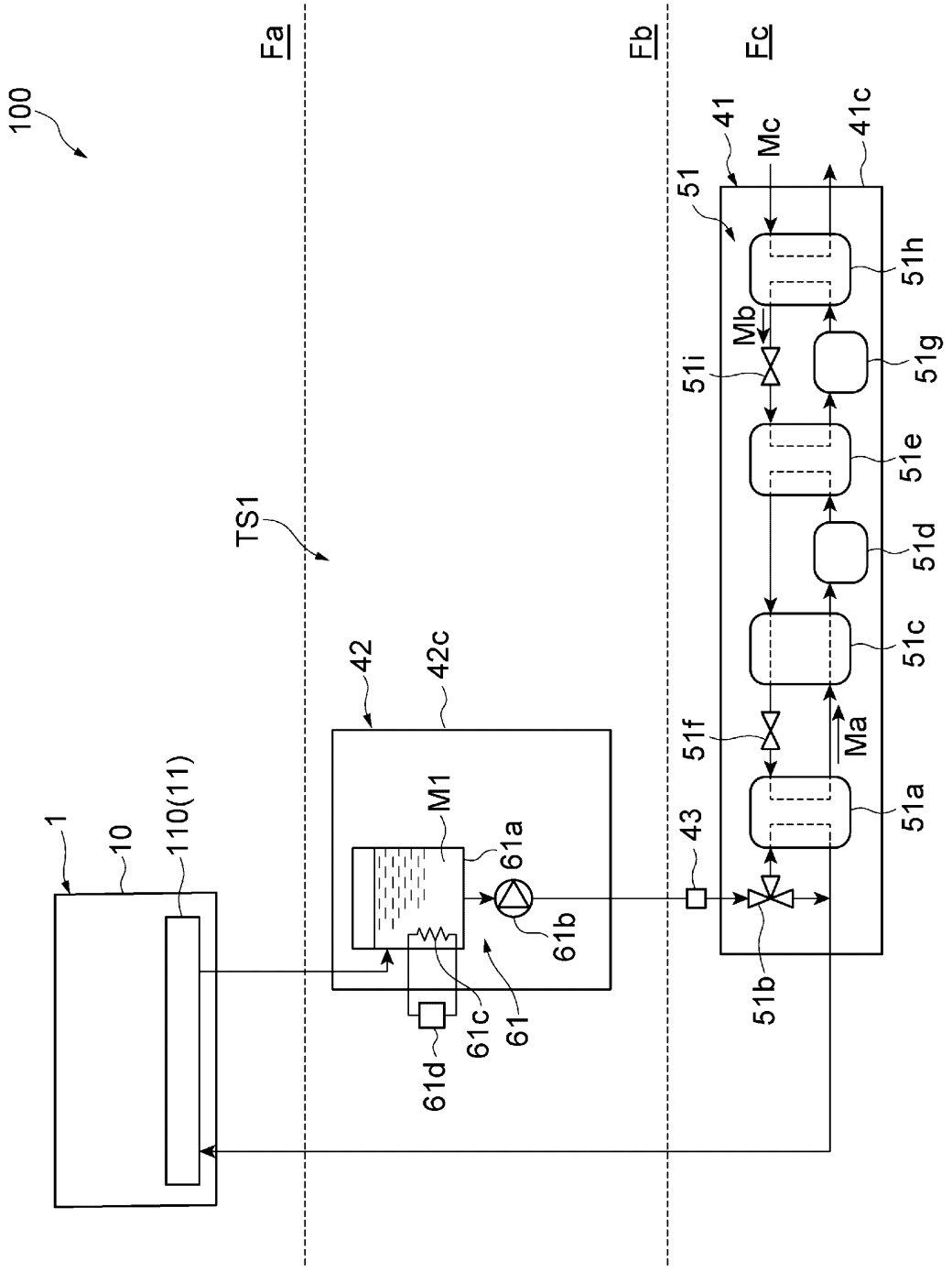

100
Fa
Fb
Fc
TS1
1
10
110(11)
42
42c
M1
61a
61b
61
61c
61d
43
41
Mc
41c
51
51h
Mb
51i
51g
51e
51d
51c
51f
Ma
51a
51b

FIG. 4

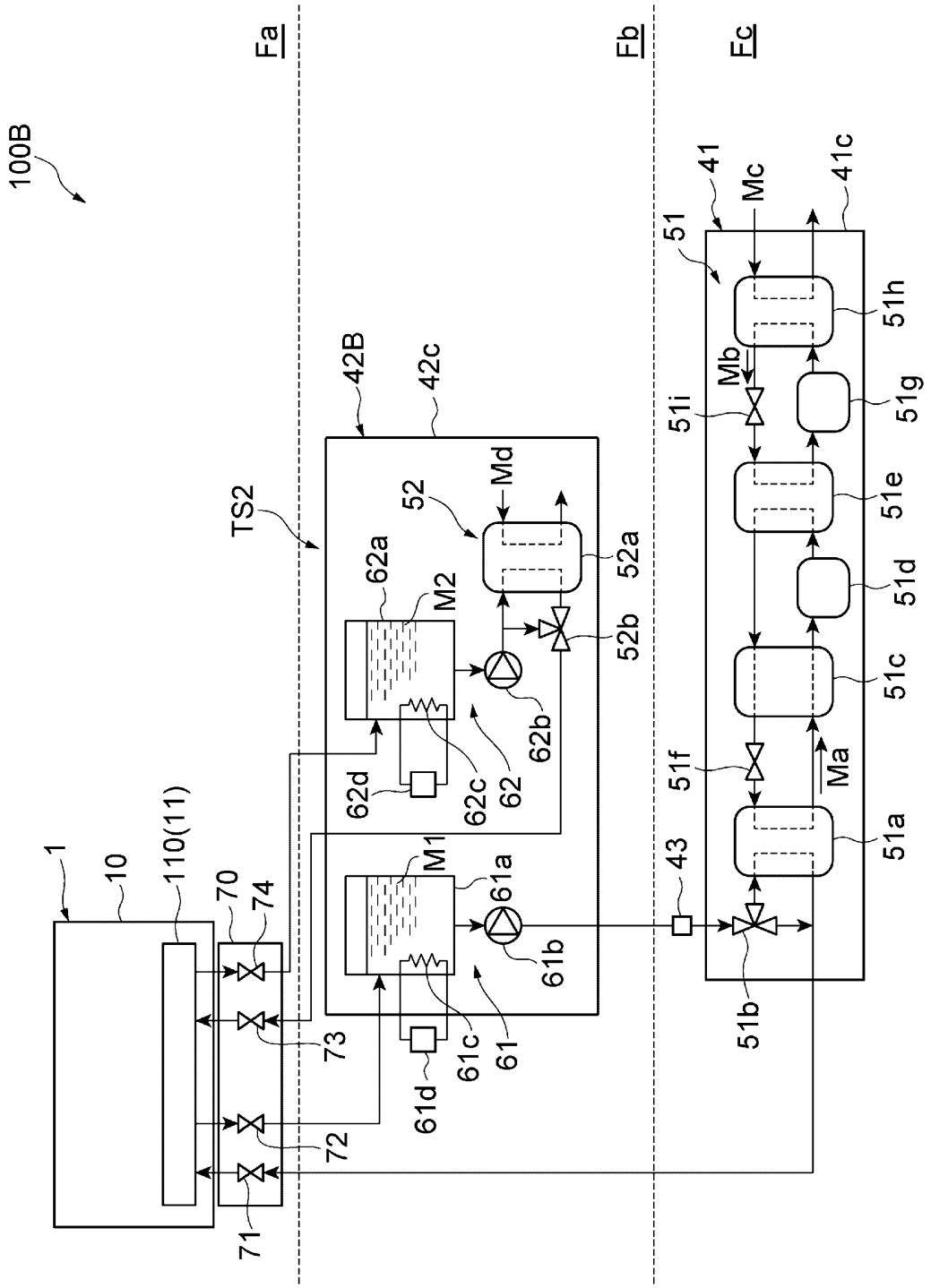

100B
Fa
Fb
Fc
1
10
110(11)
70
74
71
72
73
TS2
42B
42c
52
Md
52a
52b
62a
M2
62
62b
62c
62d
M1
61
61a
61b
61c
61d
43
41
41c
Mc
51
51h
Mb
51i
51g
51e
51d
51c
51f
Ma
51a
51b

FIG. 5

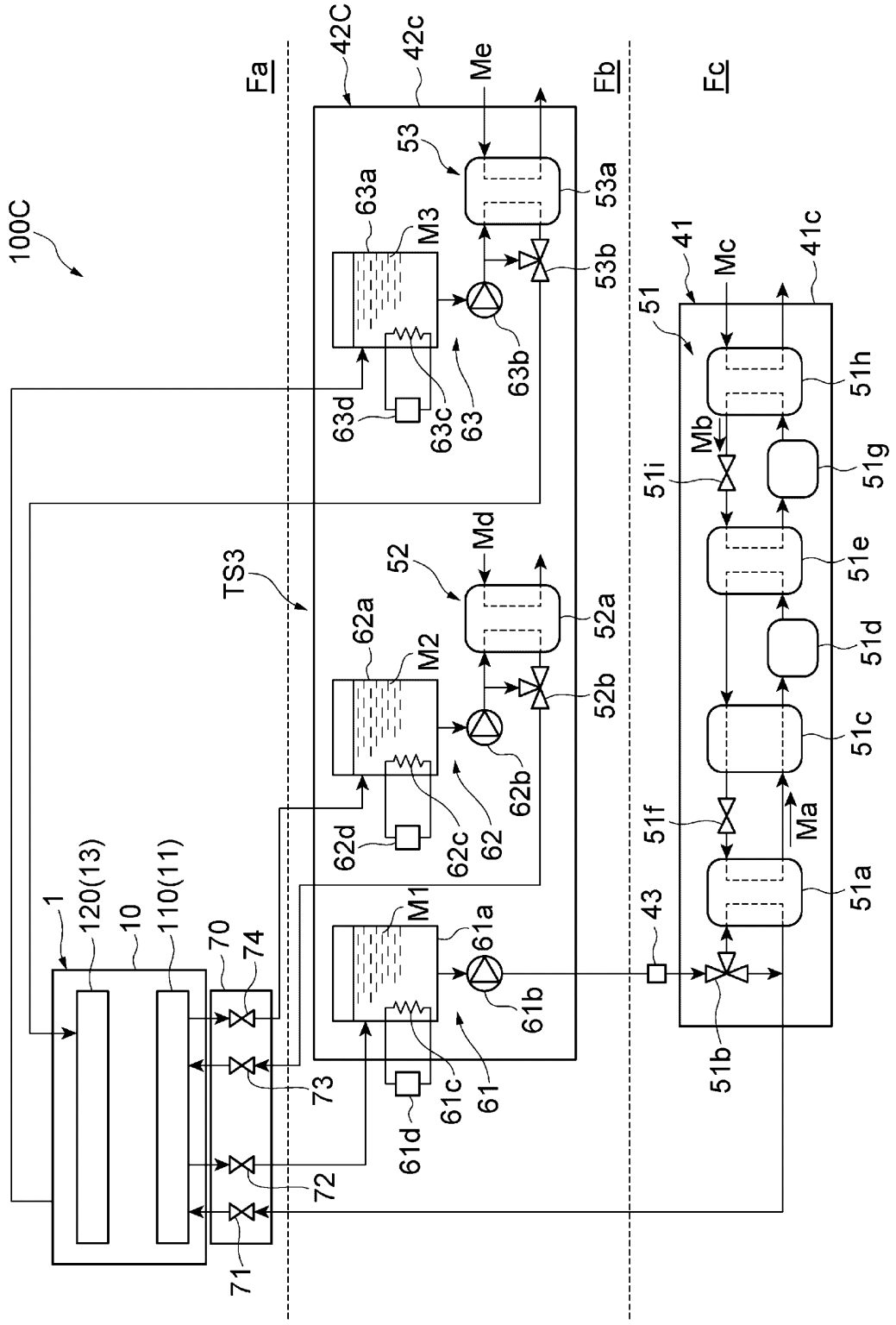

100C
Fa
Fb
Fc
42C
42c
Me
53
53a
53b
63a
M3
63b
63
63c
63d
TS3
52
Md
52a
52b
62a
M2
62b
62
62c
62d
1
120(13)
10
110(11)
70
74
73
72
71
M1
61a
61b
61
61c
61d
43
41
Mc
41c
51
51h
Mb
51i
51g
51e
51d
51c
Ma
51f
51a
51b

FIG. 6

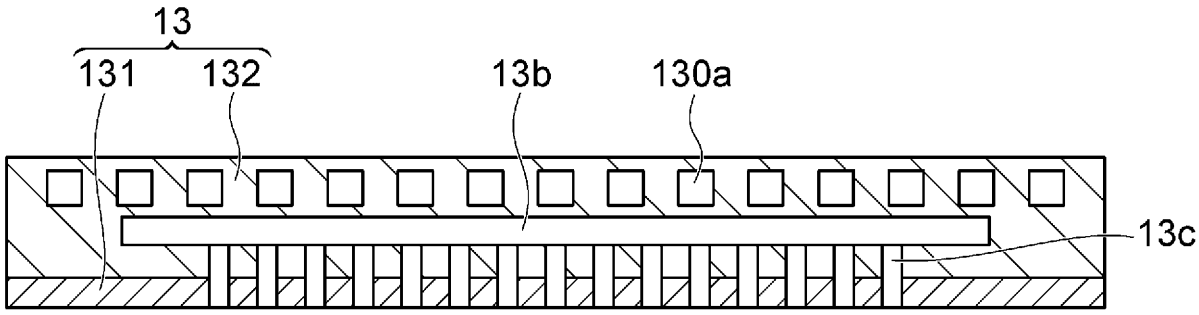
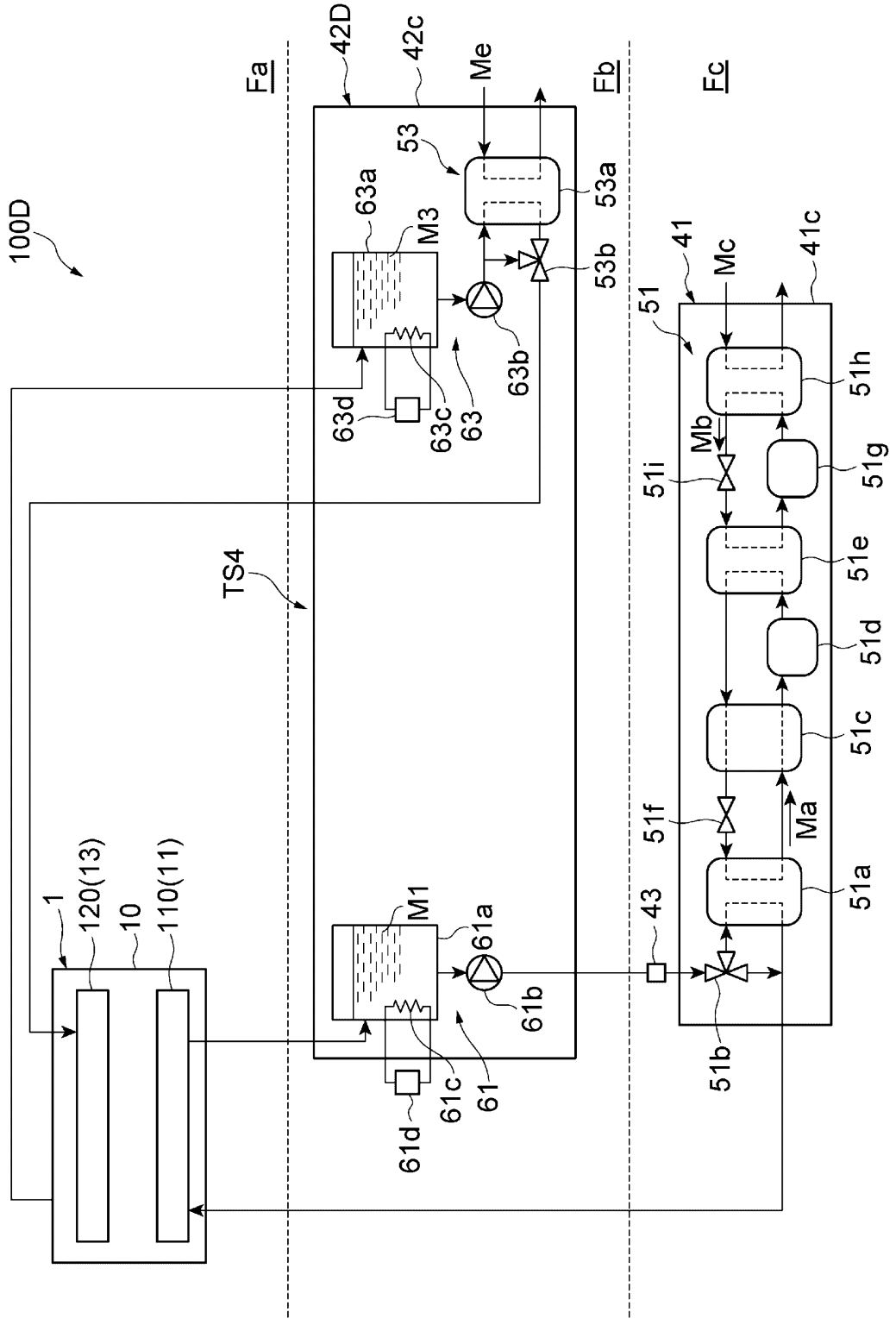


FIG. 7


100D
Fa
Fb
Fc
42D
42c
Me
53
53a
53b
63a
M3
63b
63d
63c
63
TS4
1
120(13)
10
110(11)
M1
61a
61b
61d
61c
61
43
41
Mc
41c
51
51h
Mb
51i
51g
51e
51d
51c
51f
Ma
51a
51b